SYSTA provides FAB proven RPC products for most Thin Film tools. Our RPC solutions come with professional installation and a full warranty.

Remote Plasma Cleaning
www.WetBenches.net

End users report a reasonably quick ROI:
- Up to 30% increase in throughput
- Clean Times reduced by 2X - 5X
- Up to 3X increase in the time interval between PMs
- Cost savings from improved lifetime of chamber parts
- Improved particle performance
- Eliminate 1st wafer after clean thickness variation

Ask to see the data!

RPC is now widely accepted as the leading chamber cleaning BKM by both users & OEMs.

C2F6 chamber cleaning accounts for 50%-70% of the PFCs used in semiconductor fabrication. NF3 RPC reduces global warming emissions by ~95%